PATENT APPLICATION (0) Q61045

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

hyre application of

Fumiyoshi ONO

Appln. No.: 09/672,776

Confirmation No.: Not assigned

Filed: September 29, 2000

For: COMPOSITION FOR POLISHING METAL ON SEMICONDUCTOR WAFER AND

METHOD OF USING SAME

RESPONSE UNDER 37 C.F.R. § 1.111

Group Art Unit: 1765

Examiner: C. Brown

Commissioner for Patents Washington, D.C. 20231

Sir:

This Response is submitted in response to the Office Action dated November 1, 2001, in which the Examiner set a three-month period for response.

Please consider the remarks as submitted herewith.

REMARKS

Claims 6-9 are all the claims pending in the application.

I. Response to rejection of Claims 6-9 Under 35 U.S.C. § 103(a)

On pages 2-3 of the Office Action, the Examiner rejects claims 6-9 under 35 U.S.C. 103(a) as being unpatentable over Kasai et al. (U.S. 6,007,592) in view of Sakatani et al. (U.S. 5,804,513).

Applicant respectfully traverses this rejection for the following reasons.

Initially, it appears that the Examiner has not fully appreciated the Declaration evidence submitted on August 22, 2001. The Examiner asserts that the conclusion